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(54) **SPUTTER TARGET FOR A PHYSICAL VAPOR DEPOSITION CHAMBER**

(71) Applicant: **APPLIED MATERIALS, INC.**, Santa Clara, CA (US)

(72) Inventors: **Martin Riker**, Milpitas, CA (US); **William Fruchterman**, Sunnyvale, CA (US); **Ilya Lavitsky**, Santa Clara, CA (US); **Srinivasa Rao Yedla**, Bangalore (IN); **Kirankumar Neelasandra Savandaiah**, Bangalore (IN)

(73) Assignee: **APPLIED MATERIALS, INC.**, Santa Clara, CA (US)

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(51) **LOC (13) Cl.** **15-09**

(52) **U.S. Cl.**
USPC **D15/138**; D13/182

(58) **Field of Classification Search**
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CPC H01J 37/3414; H01J 37/3423; H01L 21/02631; H01L 2221/68363; H01L 2224/75186–75189; H01L 21/67742; H01L 21/0226; H01L 21/02263; H01L 21/02266; H01L 21/02269; H01L 21/02271; F16J 7/00; E04D 13/14; C23C 14/3407; C23C 14/35
See application file for complete search history.

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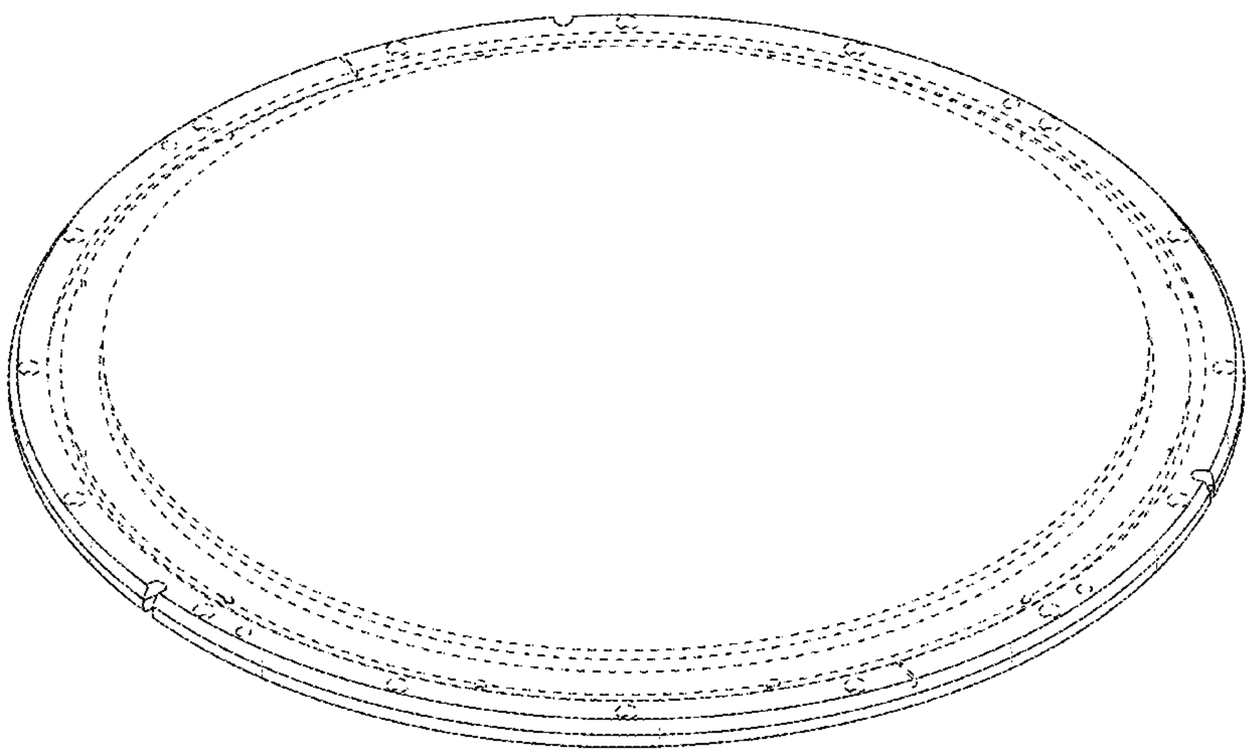

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Primary Examiner — Calvin E Vansant
Assistant Examiner — Mark T. Philipps
(74) *Attorney, Agent, or Firm* — Moser Taboada

(57) **CLAIM**

We claim the ornamental design for a sputter target for a physical vapor deposition chamber, as shown and described.

DESCRIPTION

FIG. **1** is a top isometric view of a sputter target for a physical vapor deposition chamber, according to our novel design.
FIG. **2** is a top plan view thereof.
FIG. **3** is a bottom plan view thereof.
FIG. **4** is a right elevation view thereof.
FIG. **5** is a left elevation view thereof.
FIG. **6** is a front elevation view thereof.
FIG. **7** is a back elevation view thereof; and,
FIG. **8** is an enlarged cross-sectional view taken along line **8-8** in FIG. **2**.
The dashed lines in FIGS. **1-8** represent unclaimed environment and form no part of the claimed design.

1 Claim, 5 Drawing Sheets

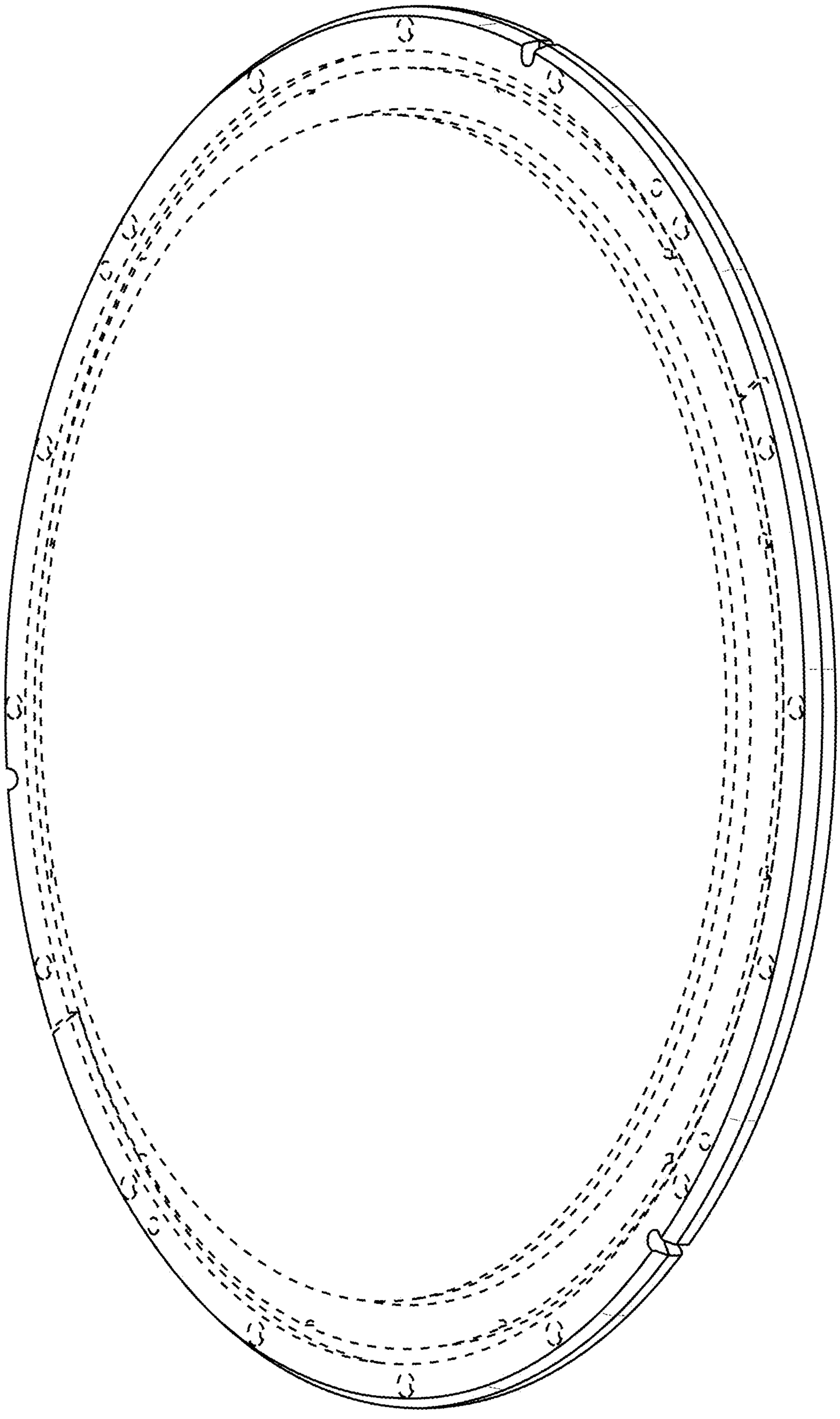

FIG. 1

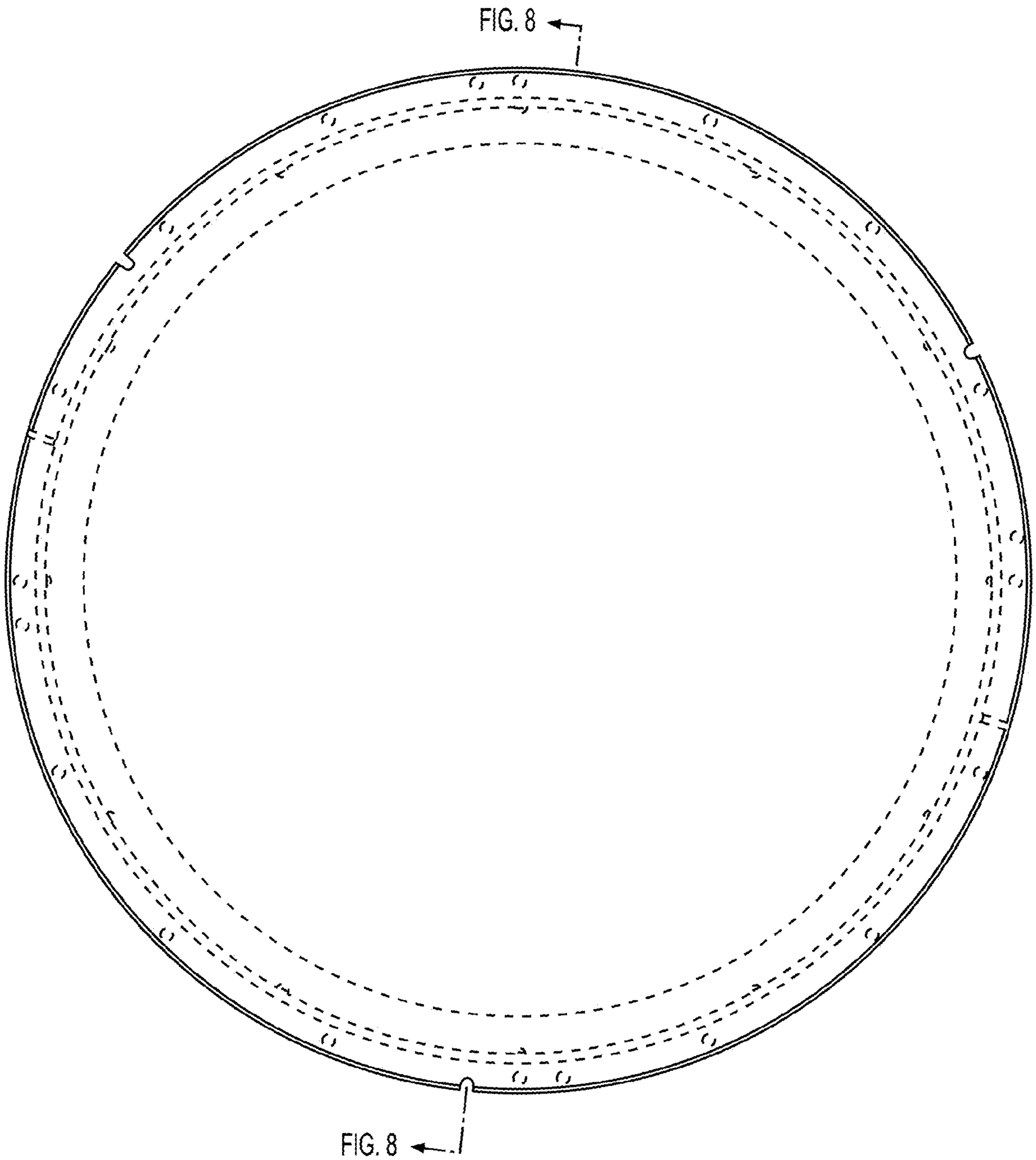

FIG. 2

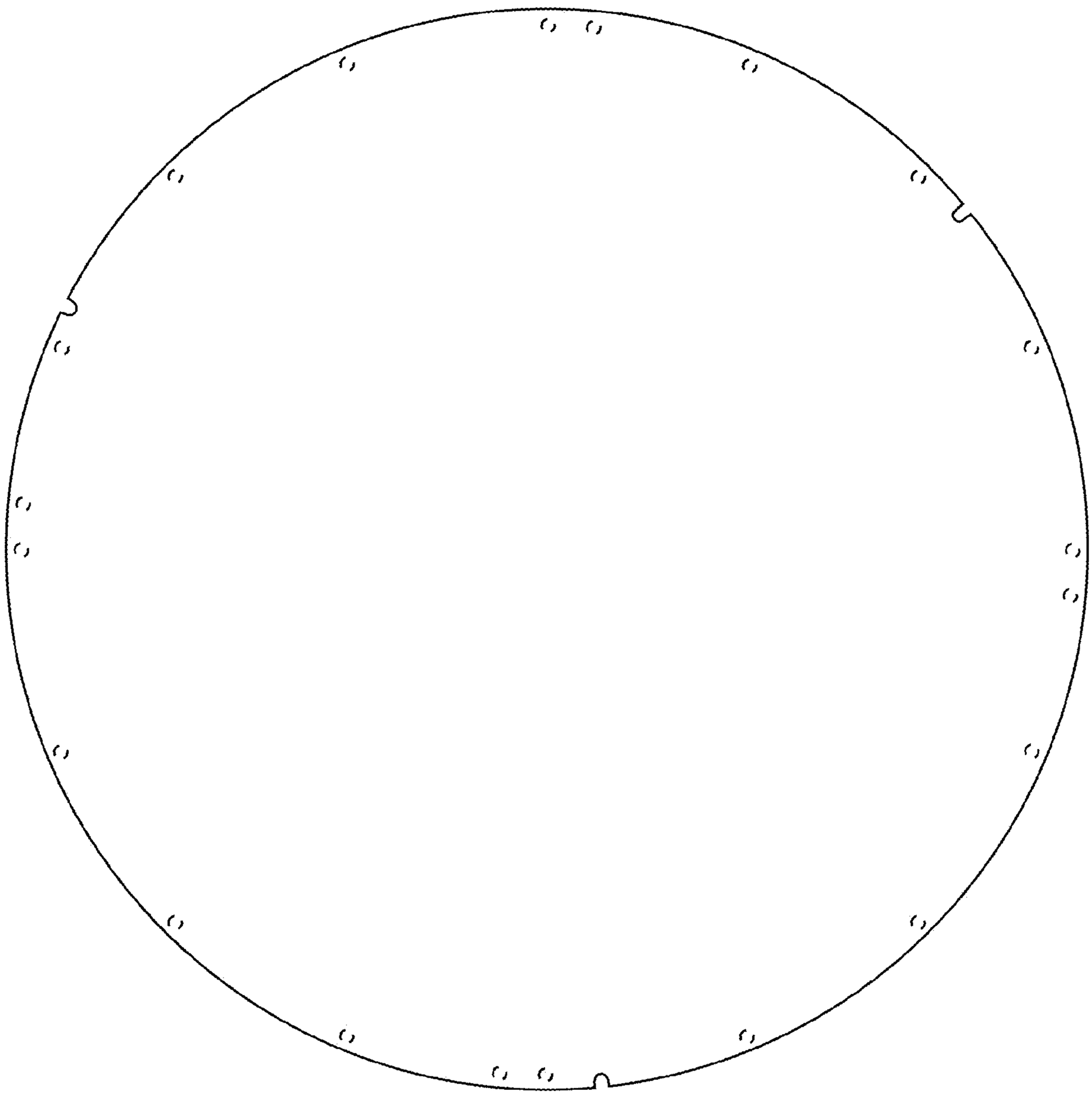

FIG. 3

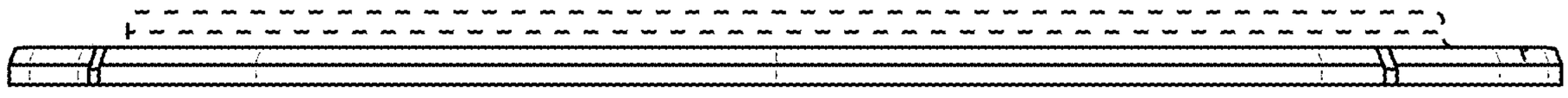

FIG. 4

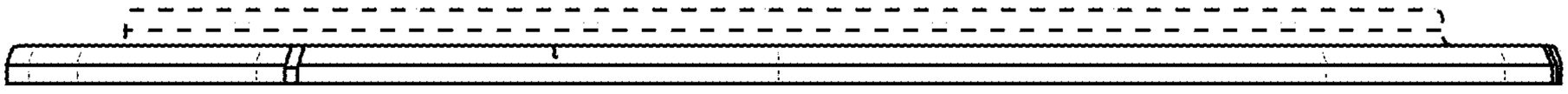

FIG. 5

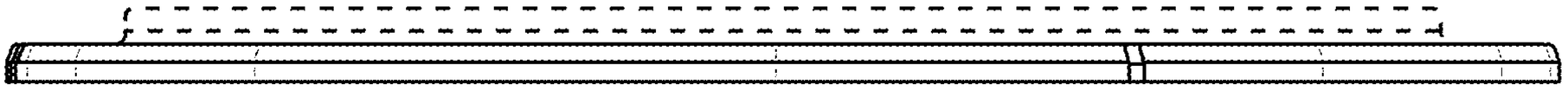

FIG. 6

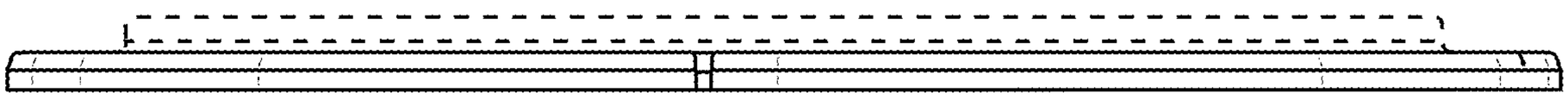

FIG. 7

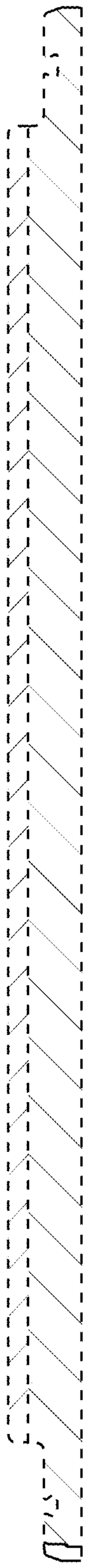

FIG. 8